

10,601,789

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Norio KIMURA et al. :
Serial No. NEW : Attn: APPLICATION BRANCH
Filed June 24, 2003 : Attorney Docket No. 2003-0865

APPARATUS FOR POLISHING A
SUBSTRATE
(Rule 1.53(b) Divisional
of Serial No. 09/897,918,
Filed July 5, 2001)

CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

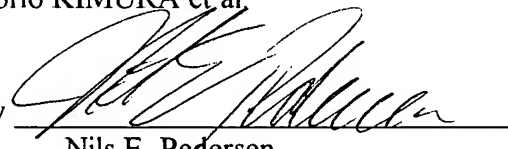
Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 203754/2000, filed July 5, 2001, as acknowledged in the Declaration of this application.

A certified copy of said Japanese Patent Application is of record in parent application Serial No. 09/897,918, filed July 5, 2001.

Respectfully submitted,

Norio KIMURA et al

By


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THE COMMISSIONER IS AUTHORIZED
TO CHARGE FEES FOR THE
ACCOUNT NO. 20-111

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June 24, 2003

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